THE UNITED STATES PATENT AND TRADEMARK OFFICE

REVOCATION AND NEW POWER OF ATTORNEY AND CHANGE OF CORRESPONDENCE ADDRESS

I, Dr. Graham Fisher, Director of Intellectual Property of MEMC Electronic Materials, Inc., the Assignee of the entire right, title, and interest in the U.S. Patent Application(s) and/or Patent(s) identified on the attached Schedule A, hereby revoke all previous powers of attorney or authorizations of agent given and do hereby appoint the attorneys or agents associated with the following Customer Number, with full power of substitution and revocation, to prosecute and transact all business in the Patent and Trademark Office connected therewith for the U.S. Patent Application(s) and/or Patent(s) listed in the attached Schedule A:

Customer Number: 76681

Please direct all correspondence in connection with said U.S. Patent Application(s) and/or Patent(s) to:

Customer Number: 76681

Respectfully submitted,

Dr. Graham Fisher
Director of Intellectual Property
MEMC Electronic Materials, Inc.

THE UNITED STATES PATENT AND TRADEMARK OFFICE

STATEMENT UNDER 37 CFR 3.73(b)

MEMC Electronic Materials, Inc., a Delaware Corporation, pursuant to 37 CFR 3.73(b), hereby states that it is the Assignee of the entire right, title, and interest in U.S. Patent Application(s) and/or Patent(s) on the attached Schedule A.

The entire rights, title, and interest in the aforementioned Patent Application(s) and/or Patent(s) were conveyed to MEMC Electronic Materials, Inc. via Assignment(s) recorded with the United States Patent and Trademark Office at the Reel/Frame Numbers on the attached Schedule A.

The undersigned, Dr. Graham Fisher, Director of Intellectual Property, has full authorization to act on behalf of Assignee MEMC Electronic Materials, Inc.

Respectfully submitted,

Date: 5/13/2008

Dr. Graham Fisher

Director of Intellectual Property
MEMC Electronic Materials, Inc.

APPENDIX A Owned by MEMC Electronic Materials, Inc.

ATTORNEY REFERENCE	CONF. NO	PUBLICATION NO. & DATE	SERIAL NO. FILING DATE	PATENT NO. ISSUE DATE	CURRENT OWNER/ ASSIGNEE	REEL AND FRAME NO.	тпсе
28744-215 (MEWC2905.16)	4312	US2007-0169693-A1 7/26/2007	11,622,142 VYS/2007		MEMC Electronic Materials, Inc.	Division of 10/380,806 recorded at 014339/0812	NITROGEN-DOPED SILICON SUBSTANTALLY FREE OF DAIDATION INDUCED STACKING FALLTS
MEMO2905.9	1990	US-2004-0009111-A1 1/15/2004	10/380,806	7,182,809	MEMC Electronic Materials, Inc.	014339/0812	NITROGEN-DOPED SILICON SUBSTANTIALLY FREE OF OXIDATION INDUCED STACKING FAULTS
MEMC2907.1	3890	US-2003-0079673-A1 5/1/2003	10/281,632 10/28/2002	6,866,713 3/15/2005	MEMC Electronic Materials, Inc.	013562/0482	SEED CRYSTALS FOR PULLING SINGLE CRYSTAL SILICON
MEMC2990_1	5778	US-2002-0100410-A1 8112002	10/054,629 1/22/2002	6,846,539 1/25/2005	MEMO Electronic Materials, Inc.	012769/0747	LOW DEFECT DENSITY SILICON HAVING A VACANCY: DOMINATED CORE SUBSTANTIALLY PREE OF OXIDATION INDUCED STACKING FAULTS
MEMC2890.9	, ett3	US-2005-0150445 A1 7/14/2005	11/005,987	7,217,320 5/15/2007	MEMIC Electronic Materials, Inc.	Division of 10/054,628 recorded at 012769/0747	Division of 10/054,628 LOW DEFECT DENSITY SILICON HAVING A VACANCY- DOMINATED CORE SUBSTANTIALLY FREE OF OXIDATION INDUCED STACKING FAULTS INDUCED STACKING FAULTS
MEMC2970.1	4314	US-2003-0061985-A.1 4/3/2003	10256,759 9/27/2002	7,132,091	MEMC Electronic Materials, inc.	013576/09515	SINGLE CRYSTAL SILICON INGOT MAVING A HIGH ARSENIC CONCENTRATION
MEWC2994.10	1088	US-2005-0255671-47	111174,908 7.622005	7,071,080 7/4/2006	MEMO Electronic Materials, Inc.	Division of 10/177,444 responded at 013181/0622	DWISION OF 10/177444 PROCESS FOR PRODUCING SILICON ON INSILATOR CONDIGION OF 10/17744 PROCESS FOR PRODUCING SILICON ON INSILATOR STRUCTURE HAVING INTRINSIC GETTERING BY ION INFLANTATION
MENC2884.2	5976	US-2003-0008435-A1 1/9/2003	101777,444	6,960,375	MEMC Electronic Materials, Inc.	013181/0822	SILICON ON INSULATOR STRUCTURE HAVING AN EPITAXIAL LAYER AND INTRINSIC GETTERING
MEM02992	2873	US-2003-0068958-A1 4/10/2003	09/682,677 10/4/2001	6,712,673 3/36/2004	Materials, inc.	012328/0298	POLISHING APPARATUS, POLISHING HEAD AND METHOD
MEMOSORA 10	2878	US-2005-0045247-A1 3/3/2005	10/963,340	7,201,990	MEMIC Electronic Materials, Inc.	Division of 10/963,340 recorded at 01.3923/01.24	DIVISION OF 10/953.340 PROCESS FOR MAKING SILICON WAFERS WITH STABILIZED RESCRIPTION CENTERS
MEMC3004.2	8328	US-2003-0136961-A7 7/24/2003	10/328,481	6,248,781 10/26/2004	MEMC Electronic Materials, inc.	0139230124	SHICON WAFERS WITH STABILIZED OXYGEN PRECIPITATE NUCLEATION CENTERS AND PROCESS FOR MAKING THE SAME
MEMCSDOS.3	1197	US-2004-0116333-A1 8/24/2004	10/699,036 10/31/2003	7,125,450 10/24/2006	MEMC Electronic Materials, inc.	2004/0[18833	PROCESS FOR PREPARING SINGLE CRYSTAL SILICON USING CRUCIBLE ROTATION TO CONTROL TEMPERATURE GRADIENT
MEMC3007	2404	US2004-0255847 A1 12/23/2004	10/465,528 6/19/2003	6,942,733 9/13/2005	MEMC Electronic Materials; Inc.	013911/0117	FLUID SEALING SYSTEM FOR A CRYSTAL PULLER
28744-107 04EMC3011.13	8422	US-2003-0192469-A1 10/16/2003	10/22/7,660		MEMC Electronic Malerials, Inc.	2003/0192459	PROCESS FOR CONTROLLING DENUDED ZONE DEPTH IN AN IDEAL OXYGEN PRECIPITATING SULCON WAFER
28744-138 (MEMC3035.1)	5409	US-2004-0112277-A1 6/17/2004	10/705,813 11/10/2003		MEMC Electronic Materials, Inc.	2004/0112277	CRYSTAL PULLER AND METHOD FOR GROWING A MONOCRYSTALLINE INGOT
MEMC3043	3340		08/3-46,695	5,668,045	MEMC Electronic Malentals, Inc.	00732140390	PROCESS FOR STRIPPING OUTER EDGE OF BESO! WAFERS